

Amendments to the Claims

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently amended) A materials reduction apparatus comprising:
 - a rotatably mounted rotor having radial projections;
 - an anvil having an operational configuration where the anvil is operationally normally fixed [[and]] in proximal relation to the projections of the rotor;
 - a conveying mechanism for conveying materials to be reduced into the rotating rotor and projections, and to be carried by said projections for impacting said anvil to reduce in size the components of said materials;
 - a screen also having an operational configuration where the screen is operationally normally fixed in proximal relation to said projections of the rotor for engaging said components to further reduce the size of the components and to provide passage of said further reduced components through screen openings in said screen and out of the path of the projections for collection and conveyance away from said apparatus;
 - said anvil and screen mounted to have common pivotal movement away from said rotor projections and as pivoted away from said projections providing a bypass for materials carried by said projections to thereby avoid anvil and screen reduction; and
 - a pivotal resist member adapted to provide providing resistance to said pivotal movement while permitting said pivotal movement and thus providing a bypass of materials in response to a determined force generated by reduction resisting components of the material, and further adapted to allow the screen and anvil to reestablish the operational configuration.
2. (Original) A material reduction apparatus as defined in Claim 1 wherein said pivotal resist member includes a bias member extended between a frame component of said

apparatus and said anvil and screen to resist said common pivotal movement of said anvil and screen.

3. (Currently amended) A material reduction apparatus as defined in Claim 1 wherein said pivotal resist member includes a latch mechanism and further including a spring biased cam member engaging a cam surface, and said reduction by said screen and anvil urges said cam member against said spring bias for retraction and release of said cam member in response to excessive reduction resistance and allows for reattaching once the material has bypassed.

4. (Original) A material reduction apparatus as defined in Claim 3 wherein said cam surface is provided by a slidable member urged into a first slidable position in a first slidable direction by a biasing member and a stop that prevents further movement in said first slidable direction, said biased cam member not urging said slidable member in said first slidable direction against said stop when said anvil and screen are urged away from said projections and said biased cam member urging said slidable member against said biasing member for closing of said bypass.

5. (Currently amended) A material reduction apparatus as defined in Claim 1 wherein said pivotal resist member is a biasing member urging the anvil and screen to the ~~normally fixed proximal position~~operational configuration and including increased resistance as the anvil and screen are pivoted away from said ~~proximal position~~operational configuration.

6. (New) A materials reduction apparatus comprising:

 a rotatably mounted rotor having radial projections;
 an anvil and at least one screen operationally fixed in proximal relation to the projections of the rotor, said anvil and screen pivotally coupled to a shaft to allow common pivotal movement away from said radial projections; and
 a compression member coupled to the shaft, the compression member adapted to allow limited linear movement of the shaft.

7. (New) A material reduction apparatus as defined in Claim 6, wherein said shaft is further coupled to a shear pin adapted to shear when a reduction resistant material is encountered that results in shaft movement that overcomes a predetermined amount of compression in the compression member.

8. (New) A material reduction apparatus as defined in Claim 6 further comprising a pivotal resist member adapted to provide resistance to said pivotal movement while permitting said pivotal movement in response to a determined force generated by a reduction resistant component, and further adapted to allow the anvil and screen to reestablish an operational configuration.

9. (New) A materials reduction apparatus comprising:

 a rotatably mounted rotor having radial projections;

 an anvil and at least one screen operationally fixed in proximal relation to the projections of the rotor, said anvil and screen pivotally coupled to a shaft to allow common pivotal movement away from said radial projections; and

 a shear pin coupled to the shaft and adapted to shear when a reduction resistant material is encountered.

10. (New) A material reduction apparatus as defined in Claim 9, wherein said shaft is further dynamically coupled to a compression member to allow limited linear movement of the shaft to allow certain reduction resistant materials to be encountered without causing the shear pin to shear.

11. (New) A material reduction apparatus as defined in Claim 9 further comprising a pivotal resist member adapted to provide resistance to said pivotal movement while permitting said pivotal movement in response to a determined force generated by a reduction resistant component, and further adapted to allow the anvil and screen to reestablish an operational configuration.